

## Special Issue

# Recent Advances in MEMS Pressure Sensors

### Message from the Guest Editors

MEMS pressure sensors are highly demanded in many fields, such as industrial processing, automobiles, daily electronic products, clinical medicine and aerospace, because of their miniature sizes, low power consumption, high sensitivity and ability to be integrated with ICs. In the past few decades, remarkable progress has been achieved in improving their performance, such as sensitivity, resolution, linearity, stability and measuring accuracy. However, with the increasing requirements and expanding scope of practical applications, new challenges are arising that require continuous efforts to address. For instance, low-pressure sensors are required to detect subtle pressure changes in clinical medicine. Ultra-low-pressure sensors are required for monitoring vacuums in MEMS processes. To address these newly raised and unmet requirements in practical applications, this Special Issue aims to collect recent advances in modeling, design, fabrication and packaging technologies for MEMS pressure sensors. Both original research and review papers are welcome.

### Guest Editors

Prof. Dr. Libo Zhao

The State Key Laboratory for Manufacturing System Engineering,  
School of Instrument Science and Technology, Xi'an Jiaotong  
University, Xi'an 710049, China

Dr. Zhikang Li

The State Key Laboratory for Manufacturing System Engineering,  
School of Instrument Science and Technology, Xi'an Jiaotong  
University, Xi'an 710049, China

### Deadline for manuscript submissions

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Editorial Office  
MDPI, Grosspeteranlage 5  
4052 Basel, Switzerland  
Tel: +41 61 683 77 34  
[micromachines@mdpi.com](mailto:micromachines@mdpi.com)

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### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

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